

■ Plasma Reactor / Cleaner



► From R&D to Production

- Removal of Organic films, surface cleaning, surface reforming and surface etching etc.
- Vacuum pump provided.
- Touch panel control.

► System Specifications

Model	V-1000XS
Plasma mode	RIE & DP
Aluminum chamber dimensions	600(W)×554(D)×440(H)
Electrode	Parallel flat stage plate : 460(W)×410(D)
Radio Frequency output power	1,000W
Oscillating frequency	13.56 MHz

■ Flexible Industrial Equipment



► Post Filling Clean Conveyor Oven

- This equipment is used for continuous heat-treating for the cassette which carried the liquid crystal(LCD) cell under the CLASS100 clean condition.
- Display, setting, and operation by the color LCD touch panel.

► System Specifications

Model	YY-384
Clean degree	Class100 by the low pressure lose HEPA filter CLASS100
Work conveyance	Intermittent processing method by a clean mesh conveyor
Operating temperature range	60℃ to 150℃
Temperature uniformity accuracy	±5℃ (at 150℃)
External dimensions	1,450(W)×7,440(L)×1,580(H)mm
PLC	Control of the chamber and conveyor by PLC